

제22회 한국반도체학술대회

2015년 2월 10일(화) - 12일(목), 인천 송도컨벤시아

C. Materials Growth & Characterization 분과

Room H
1F / 110호

2015년 2월 12일(목) 13:10-14:40

[TH2-C] III-Vs and SiGe for Electronic Devices

좌장: 박진섭 (한양대학교), 박일규 (영남대학교)

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| TH2-C-1 | 13:10-13:25 | Selective Area Growth of High Quality InP Layers on Si (001) by MOCVD
Sang-Moon Lee ^{1,2} , Bonyoung Koo ¹ , Jinsub Park ³ , and Euijoon Yoon ²
¹ Process Development Team, Semiconductor R&D Center, Samsung Electronics, ² Department of Materials Science and Engineering, Seoul National University, ³ Department of Electronics and Computer Engineering, Hanyang University |
| TH2-C-2 | 13:25-13:40 | Reduction of Dark Current in InSb Photodiode through Band Alignment Engineering of Barrier Layer
Hwanyeol Park ¹ , Sehun Park ¹ , Yongjo Park ² , and Euijoon Yoon ^{1, 2}
¹ Department of Materials Science and Engineering and Inter-university Semiconductor Research Center, Seoul National University, ² Energy Semiconductor Research Center, Advanced Institutes of Convergence Technology, Seoul National University |
| TH2-C-3 | 13:40-13:55 | Oxygen Vacancy-Nitrogen Complex in Nitrogen-Doped Hafnium Oxide
Mino Yang and Hionsuck Baik
Analytical research division, Korean Basic Science Institute |
| TH2-C-4 | 13:55-14:10 | Strain Measurement in MOSFET Structures with Si_{1-x}C_x S/D upon Thermal Annealing Process
Sun-Wook Kim ¹ , Dae-Seop Byun ¹ , Mijin Jung ¹ , Hoo-Jeong Lee ² , and Dae-Hong ¹
¹ Department of Materials Science and Engineering, Yonsei University, ² Department of Advanced Materials Science and Engineering, Sungkyunkwan University |
| TH2-C-5 | 14:10-14:25 | MBE Growth of III-V based Materials and its Applications to 2D/1D/0D Structures
Jin Dong Song
Nano Convergence Device Center, KIST |
| TH2-C-6 | 14:25-14:40 | Interfacial Layer Control by Dry Cleaning Technology for Polycrystalline and Single Crystalline Silicon Growth
Dong-Hyun Im ^{1,2} , Kong-Soo Lee ¹ , Yoongoo Kang ¹ , Jinwon Ma ¹ , Jamin Koo ¹ , |

The 22nd Korean Conference on Semiconductors (KCS 2015)

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Jun-Noh Lee¹, Yoonchul Cho¹, Wonseok Yoo¹, Bonghyun Kim¹, Hanjin Lim¹,
Seokwoo Nam¹, and Jeong Yong Lee²

¹Process Development Team, Semiconductor R&D Center, Samsung
Electronics Co., Ltd., ²Department of Materials Science and Engineering,
KAIST